

Fig. S1. SEM images of complex silicon patterns with period of (a) 7 μm (b) 31 μm (c) 48 μm.

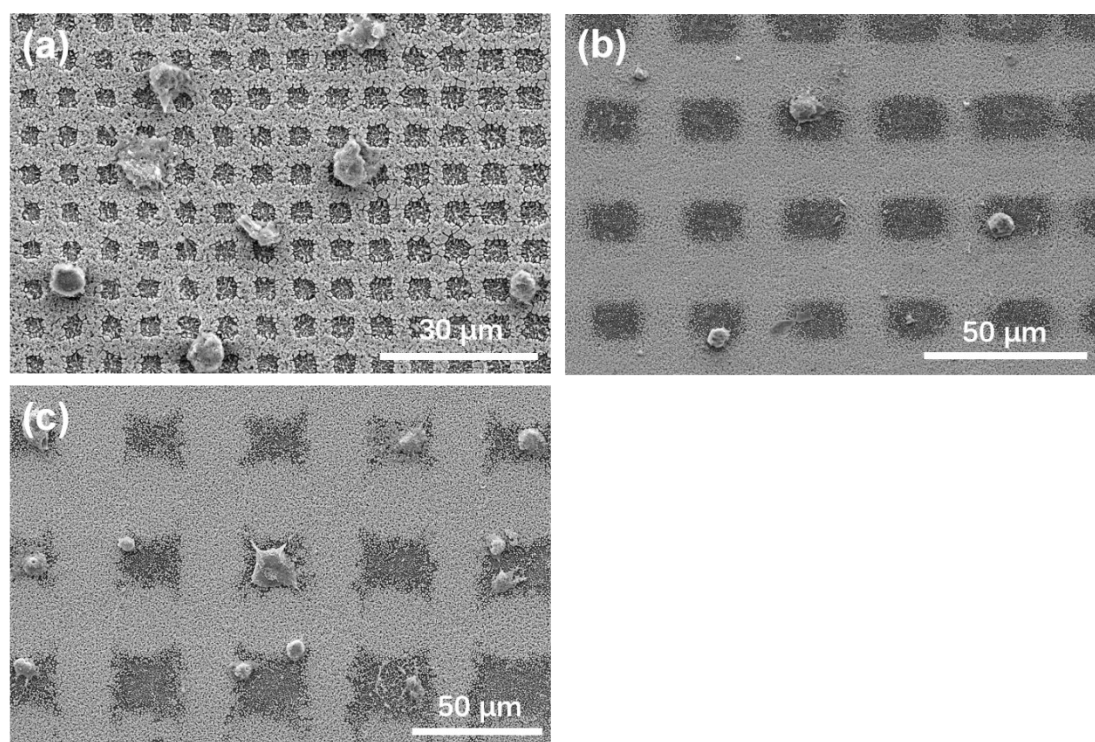


Fig. S2. SEM images of cells cultured on the grid structures with period of (a) 7 μm (b) 31 μm (c) 48 μm.